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(54) Title: FLUID DELIVERY MODULE

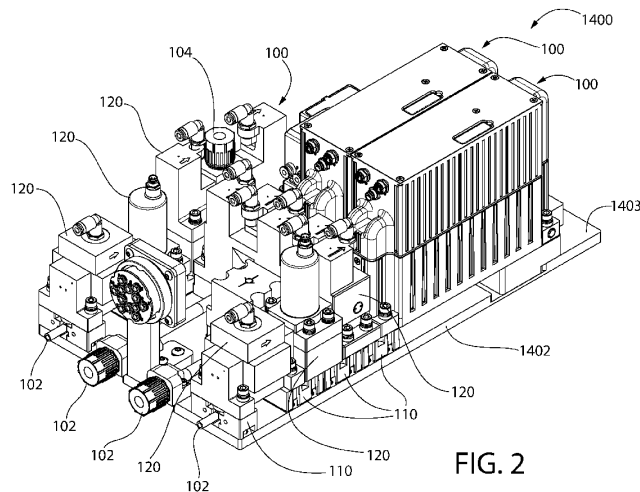


FIG. 2

(57) Abstract: Apparatuses for controlling fluid flow are important components for delivering process fluids for semiconductor fabrication. These apparatuses for controlling fluid flow are formed with a variety of fluid flow components, including fluid flow components for mixing fluid flows. Fluid flow components for mixing flows utilize mixing elements configured to receive flows of two or more process fluid flows via fluid inlets, mix the fluid flow within the mixing element, and deliver mixed fluid to a down-stream fluid flow component or an outlet of an apparatus for controlling fluid flow.

[Continued on next page]

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